

Electrical scanning probe microscopy approaches to investigate solar cell junctions and devices

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Electrical SPM Research Activities @ Careers

High power and high temperature devices



J. Alvarez and al. Superlattice Microst. 40, 343-349 (2006)

Evidencing leakage current in diamond Schottky devices



Deep UV photodetection





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Atomic Force Microscopy (AFM) setup



Kelvin probe force microscopy (KPFM) : -contact potential difference (CPD) and surface photovoltage (SPV) mapping



-local current and photocurrent mapping



Part 1 - Hydrogenated amorphous silicon/crystalline silicon heterojunction Part 2 - Passivating selective contacts: (p+) Poly-Si/SiOx/c-Si Part 3 - P-I-N radial junctions (RJ) Silicon Nanowires (SiNWs)

Part 1

Hydrogenated amorphous silicon/crystalline silicon heterojunction



- Sa-Si:H/c-Si Heterojunction solar cells "Si-HET" was first studied by Sanyo in the 80's [1]
- Seducing recombination at the interfaces Si-HET has achieved the highest efficiency for c-Si tech. : 26.3-26.7% [2,3]

[1] Hamakawa et al., Appl. Phys. Lett. 43, 644 (1983)
[2] Yoshikawa et al., Nat. Energy 2, 17032 (2017)
[3] Yamamoto et al., Japan. J. Appl. Phys. 57, 08RB20 (2018)

1.1 Motivation : Interface Band lineup



due to strong inversion or 2D-hole gas

S a-Si:H/c-Si (N/p or P/n) studied by capacitance and planar conductance measurements suggest the presence of a strong inversion layer at the interface



Sonsidering the different current pathways only the high conductance at the a-Si:H/c-Si interface can explain the very low E_A of the Arrhenius plot.

1.3 Conductive-AFM (C-AFM) approach (1/3)

§ Sample preparation for cross-sectional investigations

- Cleavage and HF (1%) trench dipping



1.3 Conductive-AFM (C-AFM) approach (2/3)

§ Cross-sectional mapping





1.3 Conductive-AFM (C-AFM) approach (3/3)

S Comparison b/w experimental C-AFM and modelling AFORS-HET



- Resistivity profile calculations confirm the qualitative C-AFM observations

Part 1 - Hydrogenated amorphous silicon/crystalline silicon heterojunction Part 2 - Passivating selective contacts: (p+) Poly-Si/SiOx/c-Si Part 3 - P-I-N radial junctions (RJ) Silicon Nanowires (SiNWs)

Part 2 Passivating selective contacts: (p+) Poly-Si/SiOx/c-Si



Poly-Si passivating contact studied in the 80's [1,2]
 2016 – present : Intensively studied by many research groups (Fraunhoffer ISE, ISFH, NREL, INES-CEA...)
 Poduce back contact recombination losses reaching

⇐ Reduce back contact recombination losses reaching efficiencies in the range 25-26.1% [3][4]

[1] Yablonovitch et al., APL 47(11), 1211–1213 (1985)
[2] Van Halen et al., IEEE Trans. Elec. Dev. 32(7), 1307–1313 (1985)
[3] Richter et al., Sol. Energy Mater. Sol. Cells 173, 96–105 (2017)
[4] Haase et al., Sol. Energy Mater. Sol. Cells 186, 184–193 (2018)

2.1 Motivation : conduction mechanisms across the structure?



2.2 Conductive – AFM (C-AFM) approach



- Lancaster et al., Energy procedia 92, 116-121 (2016)



"Inconsistent with the selective etching approach" Pinholes density ~ 0.1-2 μ m⁻²



Zhang et al., Sol. Energy Mater. Sol. Cells 187, 113-122 (2018)



Wietler et al., Appl. Phys. Lett. 110, 253902 (2017)

S Lack of understanding of the C-AFM measurement !

2.3 C-AFM: new experiments on (p+) poly-Si/SiOx/c-Si (n) (1/3)

§ C-AFM versus surface preparation



- Deoxidation of the poly-Si surface is a requirement

2.3 C-AFM: new experiments on (p+) poly-Si/SiOx/c-Si (n) (2/3)

§ C-AFM versus annealing temperature



- Current peaks (CP) > 100 pA, densities ~10-100 μ m⁻²

C-AFM does not allow to discriminate the conduction through the pinholes

2.3 C-AFM : new experiments on (p+) poly-Si/SiOx/c-Si (n) (3/3)

§ C-AFM with and without passivating oxide



≥ C-AFM reflects poly-Si conduction inhomogeneities (surface morphology, doping...)

2.4 KPFM : new approach for (p+) poly-Si/SiOx/c-Si (1/3)

Section 2018 KPFM sensitive to the workfunction and the doping
ECV measurements on (p+) poly-Si/SiOx/c-Si



2.4 KPFM : new approach for (p+) poly-Si/SiOx/c-Si (1/3)

§ KPFM sensitive to the workfunction and the doping



2.4 KPFM : new approach for (p+) poly-Si/SiOx/c-Si (1/3)

§ KPFM sensitive to the workfunction and the doping



- Deoxidation minimizes screening effects : potential drops on the poly-Si surface => Indirect pinhole observation?

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2.4 KPFM : new approach for (p+) poly-Si/SiOx/c-Si (2/3)

§ KPFM with and without passivating oxide



- Local potential drops observed only with passivating oxide

2.4 KPFM : new approach for (p+) poly-Si/SiOx/c-Si (3/3)

§ KPFM and potential drops density



Potential drops density : $0.2 - 0.5 \,\mu m^{-2}$



Wietler et al., Appl. Phys. Lett. 110, 253902 (2017)

Pinholes density ~ 0.1-2 μ m⁻²

-Potential drops density similar to literature pinhole density by selective chemical etching

2.5 Correlative C-AFM and KPFM on intrinsic Poly-Si/SiOx/c-Si

Sample with an intrinsic top poly-Si layer





- Some local potential drops correlate well with current peaks (CPs)
- CAFM CPs reflect here conduction heterogeneities including the pinholes
- Correlations were possible due to the intrinsic layer that minimizes lateral conduction

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Part 3 P-I-N radial junctions (RJ) Silicon Nanowires (SiNWs)



[1] Misra et al., IEEE JPV 5(1), 40–45 (2015).

- NWs promising route for enhancing solar performances
 : less material; more efficient separation/collection of photocarriers
- S RJ technology "orthogonalizes " the light absorption and the minority carrier collection
- Solution Highly doped SiNWs grown by VLS using Sn catalysts with conformal deposition of (i) and (n) a-Si:H, and ITO.
- S Efficiencies up to 9.6% [1] have been demonstrated
- S Improvements require a better understanding of the individual nanodevice

3.1 Evaluation of local open-circuit voltage on single RJ SiNW by KPFM

Surface PhotoVoltage (SPV) very effective technique to image the V_{OC} of solar cells

- **§** 1st approach, SPV extracted by KPFM on completed devices and comparison with V_{oc} by I-V
- § 2nd approach, SPV measurements by KPFM (only) on isolated RJs where the SiNW device



1st approach on completed devices



2nd approach on single RJs without ITO

3.2 1st approach : KPFM and I-V measurement analysis (1/2)



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3.2 1st approach : KPFM and I-V measurement analysis (2/2)

§ V_{oc} and SPV versus light power for two different devices



- SPV and V_{oc} show linear behavior versus light power (log scale) with max. deviation b/w 2-5%.
- Ideality factor $n : 1.5 \pm 0.1$ (dev. 1) and 1.75 ± 0.25 (dev.2) in line with a-Si:H planar devices

3.3 2nd approach : KPFM on single, isolated RJs (1/3)





 Lowest SPV are observed in regions where the NWs appear the smallest

3.3 2nd approach : KPFM on single, isolated RJs (2/3)



3.3 2nd approach : KPFM on single, isolated RJs (2/3)



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3.3 2nd approach : KPFM on single, isolated RJs (2/3)



3.3 2nd approach : KPFM on single, isolated RJs (3/3)

Surface photovoltage Spectroscopy (SPS)



- SPS curves show large differences :

- w/o ITO "single, isolated SiNW RJ" cannot reflect the optimal V_{OC} value

- SPV is here impacted by a band-bending at the surface

(no FB conditions) linked to defects or dipoles formation

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Electrical AFM provides a unique chance to measure local properties of matter and characterize interfaces, junction and nanodevices.

- S Cross-sectional analysis applied on a-Si:H/c-Si allow to confirm the presence of the inversion layer suggested by macroscopic measurements.
- SC-AFM is not the best approach to investigate (p+) Poly-Si/SiOx/c-Si. KPFM allows to observe local potential drops that are expected to be an indirect observation of the dopant diffusion through the existing pinholes.
- SPV measurements by KPFM allows to get access to the V_{OC} in P-I-N RJ SiNWs only on completed devices. W/o ITO "single, isolated SiNW RJ" cannot reflect the optimal V_{OC} due that surface band bending negatively impacts SPV measurement.

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